

ABSTRACT

Clamped Monolithic Showerhead Electrode

5 An electrode assembly for a plasma reaction chamber used in semiconductor
substrate processing. The assembly includes an upper showerhead electrode which is
mechanically attached to a backing plate by a series of spaced apart cam locks. A
guard ring surrounds the backing plate and is movable to positions at which openings
in the guard ring align with openings in the backing plate so that the cam locks can be
10 rotated with a tool to release locking pins extending from the upper face of the
showerhead electrode.

FIG. 5

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